



Atty. Dkt. No.	M#	Client Ref.
	306640	P-0390.010-US

**INFORMATION DISCLOSURE STATEMENT  
 BY APPLICANT**

Applicant: DIERICHS et al.	
Appln. No.: 10/719,009	
Filing Date: November 24, 2003	
Examiner: NOT ASSIGNED	Group Art Unit: 2874

Date: May 28, 2004      Page 1 of 1

**U.S. PATENT DOCUMENTS**

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
JM	AR	5,257,132	10/1993	Ceglio et al.			
	BR						
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						
	OR						

**FOREIGN PATENT DOCUMENTS**

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
	PR								
	QR								
	RR								
	SR								
	TR								
	UR								
	VR								

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

	WR								
	XR								
	YR								
	ZR								
	AAR								
	BBR								
	CCR								

Examiner /John McPherson/      Date Considered: 06/21/2006

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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Date: November 24, 2003 Page 1 of 1

**U.S. PATENT DOCUMENTS**

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
JM	AR	5,328,784	07/1994	FUKUDA			
JM	BR	6,007,888	12/1999	KIME			
JM	CR	6,375,870	04/2002	VISOVSKY et al.			
JM	DR	6,392,792	05/2002	NAULLEAU			
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						
	OR						

**FOREIGN PATENT DOCUMENTS**

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
JM	PR	2001-100018	04/2001	JAPAN	MAEHARA HIROSHI	X			
	QR								
	RR								
	SR								
	TR								
	UR								
	VR								

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

JM	WR	Nguyen et al., "Imaging of extreme ultraviolet lithographic masks with programmed substrate defects," <i>J. Vac. Sci. Technol. B</i> 12(6):3833-3840, XP-002096163 (1994)							
	XR								
	YR								
	ZR								
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	BBR								
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